IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: ONO, Yoshinobu et al

Conf.:

Appl. No.:

NEW

Group:

Filed:

January 17, 2002

Examiner:

For:

METHOD FOR FABRICATING III-V COMPUND

SEMICONDUCTOR

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents Washington, DC 20231

January 17, 2002

Sir:

following preliminary amendments and remarks The respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please amend the claims as follows:

4. (Amended) A method for fabricating a III-V Group compound semiconductor as claimed in claim 1, further comprising a step of forming on the second layer by epitaxial growth at least one $Al_{yj}Ga_{1-yj}$ As layer (0 \leq yj<1, j=1, 2, ...).

ADM/ka

3885-0103P Attachments

REMARKS

Entry of the above amendments is earnestly solicited. An early and favorable first action on the merits is earnestly solicited.

Attached hereto is a marked-up version of the changes made to the application by this Amendment.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to Deposit Account No. 02-2448 for any additional fees required under 37 C.F.R. § 1.16 or under 37 C.F.R. § 1.17; particularly, extension of time fees.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP

P.O. Box 747

Falls Church, VA 22040-0747

(703) 205-8000

(Rev. 12/19/01)

VERSION WITH MARKINGS TO SHOW CHANGES MADE

IN THE CLAIMS:

The claims have been amended as follows:

4. (Amended) A method for fabricating a III-V Group compound semiconductor as claimed in [claim 1, 2 or 3] claim 1, further comprising a step of forming on the second layer by epitaxial growth at least one $Al_{yj}Ga_{1-yj}$ As layer (0 \leq yj<1, j=1, 2, ...).